

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Alexander Tregub et al.      Art Unit: 1711  
Serial No.: 10/799,928      Examiner: N. Nutter  
Filed : March 12, 2004  
Assignee : Intel Corporation  
Title : USE OF ALTERNATIVE POLYMER MATERIALS FOR "SOFT"  
POLYMER PELLICLES

**MAIL STOP AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Applicants call attention to the attached Information Disclosure Statement and documents listed on form PTO-1449.

The documents are in the English language; hence no concise explanation is necessary per Rule 98(a)(3).

Consideration of the foregoing and enclosures plus the return of a copy of the enclosed form PTO-1449 with the Examiner's initials in the left column per MPEP 609 are earnestly solicited along with an early action on the merits.

CERTIFICATE OF MAILING BY FIRST CLASS MAIL

I hereby certify under 37 CFR §1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

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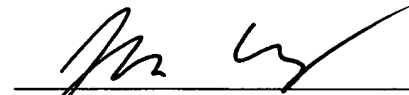
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Kindly accept this Information Disclosure Statement under Rule 97(c)(2). Please apply the rule 17(p) certification fee in the amount of \$180 to Deposit Account No. 06-1050.

Respectfully submitted,

Date: August 4, 2006

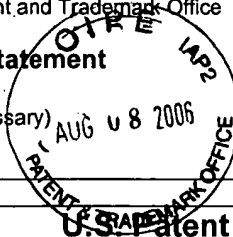
  
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Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 10559-895001	Application No. 10/799,928
<b>Information Disclosure Statement by Applicant</b> (Use several sheets if necessary) (37 CFR §1.98(b))		Applicant Alexander Tregub et al.	
		Filing Date March 12, 2004	Group Art Unit 1711



U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA	2001/0004508	06/2001	Shirasaki			
	AB	2001/0014375	08/2001	Tanaka			
	AC	2002/0136965	09/2002	Tsumoto et al.			
	AD	2002/0179852	12/2002	Zheng et al.			
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	AG	2003/0192567	10/2003	Koizumi et al.			
	AH	2004/0123950	07/2004	Boyd			
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	AM	4,737,387	04/1988	Yen			
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	AZ	6,652,958	11/2003	Tobita			
	BA	6,822,731	11/2004	Laganza et al.			

Examiner Signature	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

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U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	BB	6,841,312	01/2005	Kalk			
	BC	6,842,227	01/2005	Shu			
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Foreign Patent Documents or Published Foreign Patent Applications								
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	BF	0 252 673	01/1988	Europe				
	BG	0 416 528	03/1991	Europe				
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	BI	0 529 827	03/1993	Europe				
	BJ	0 942 325	09/1999	Europe				
	BK	09-005982	01/1997	Japan				
	BL	2005/022259	03/2005	WIPO				

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
	BM	Chen, et al., "Pellicle-Induced Reticle Distortion: An Experimental Investigation", <i>Proc. of SPIE - The Int'l Soc. for Optical Engineering</i> , Vol. 3546, pp. 167-172 (1998).
	BN	Cotte, et al., "Effects of Soft Pellicle Frame Curvature and Mounting Process on Pellicle-Induced Distortions in Advanced Photomasks", <i>Proc. of SPIE - The Int'l Soc. for Optical Engineering</i> , Vol. 5040, pp. 1044-1054 (2003).
	BO	Cotte, et al., "Experimental and Numerical Studies of the Effects of Materials and Attachment Conditions on Pellicle-Induced Distortions in Advanced Photomasks", <i>Proc. of SPIE - The Int'l Soc. for Optical Engineering</i> , Vol. 4754, pp. 579-588 (2002).
	BP	Cotte, et al., "Numerical and Experimental Studies of Pellicle-Induced Photomask Distortions", <i>Proc. of SPIE - The Int'l Soc. for Optical Engineering</i> , Vol. 4562, pp. 641-651 (2002).
	BQ	Kozeki, T., et al., "Longevity of 193nm/ArF Excimer Pellicle", Mitsui Chemicals, Inc., Pellicle Dept., pp. 1-17 (2001).
	BR	Oshima, et al., "Chemical structure and physical properties of radiation-induced crosslinking of polytetrafluoroethylene", <i>Radiation Physics and Chemistry</i> , vol. 62, pp.39-45 (2001).
	BS	Reu, et al., "Mechanical analysis of hard pellicles for 157 nm lithography", <i>Proc. of the 2001 SPIE Symp. on Optical Microlithography XIV</i> , vol. 4346, 9 pages (2001).

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Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
	BT	Shu, et al., "Hard Pellicle Study for 157-nm Lithography", <i>Preprint, to appear in the Proceedings of Photomask Japan</i> , pp. 1-12 (2002).
	BU	Van Krevelen, D.W., with the collaboration of P.J. Hoftyzer, <u>Properties of Polymers, Their Estimation and Correlation with Chemical Structure</u> , Elsevier Scientific Publishing Company, Amsterdam – Oxford – New York, pp. 68-73 (1976).

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